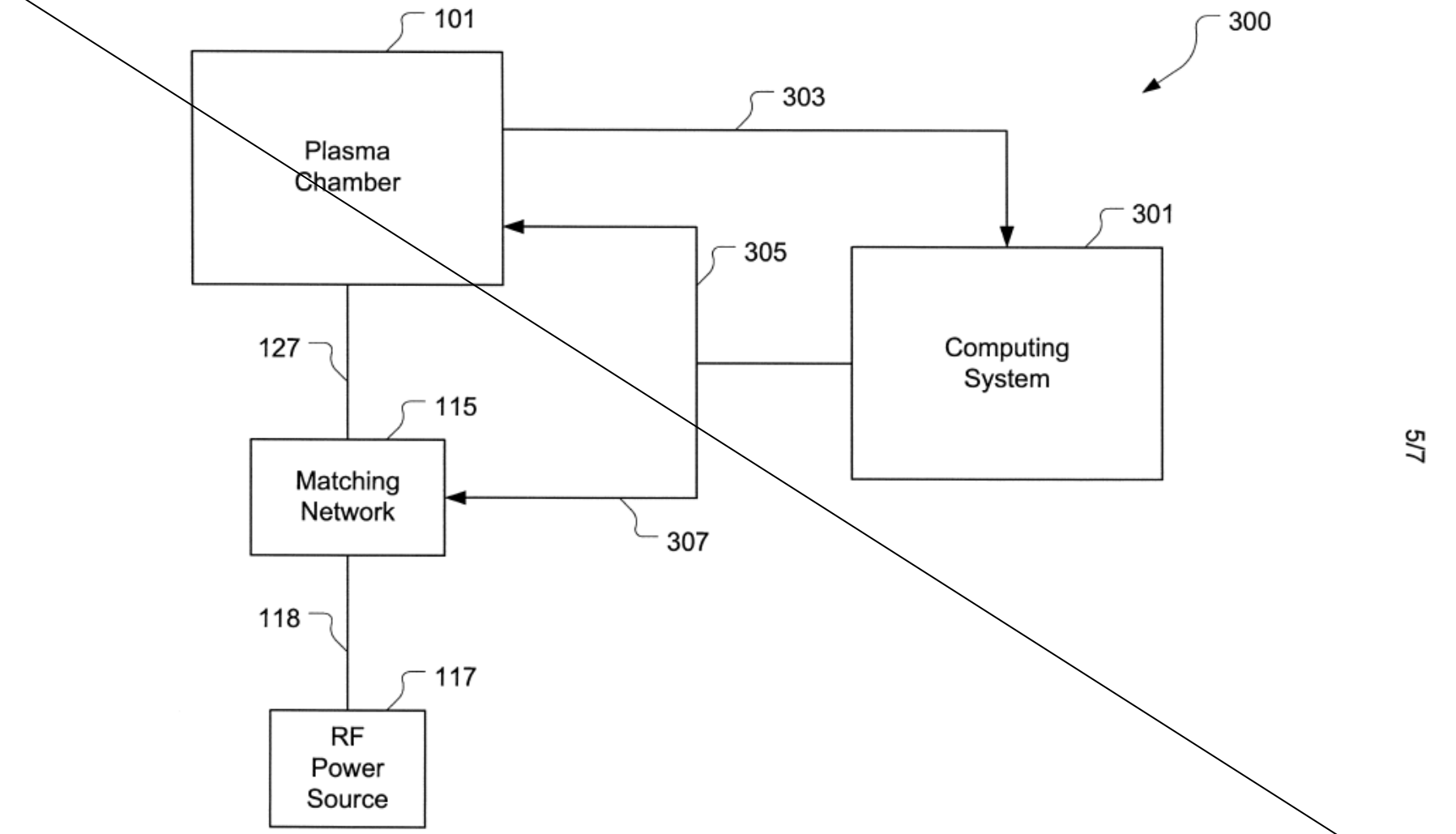

101
300
303
Plasma
Chamber
301
305
Computing
System
127
115
Matching
Network
307
118
117
RF
Power
Source

Fig. 3

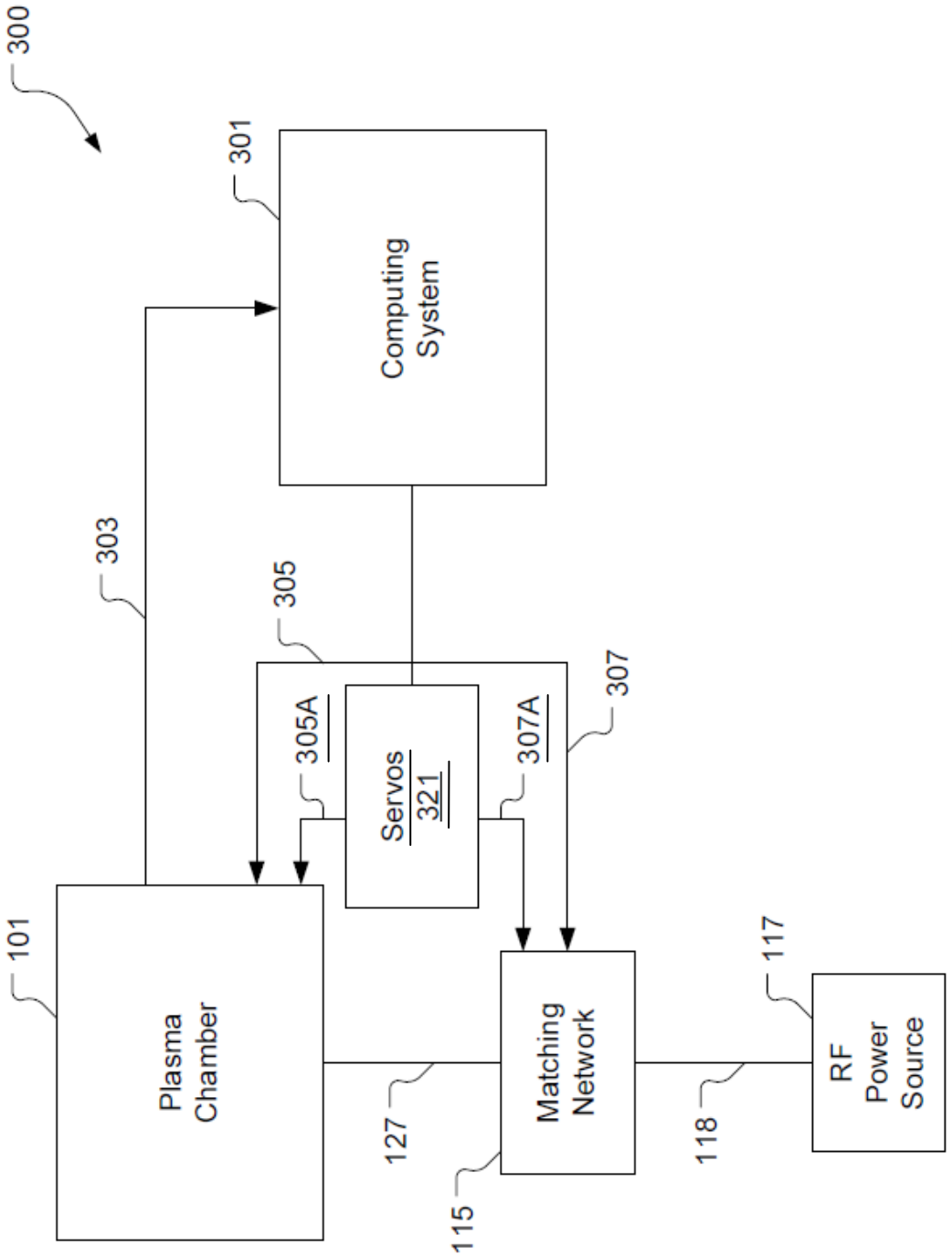

300
301
Computing System
303
305
305A
Servos 321
307
307A
101
Plasma Chamber
127
115
Matching Network
117
118
RF Power Source

Fig. 3